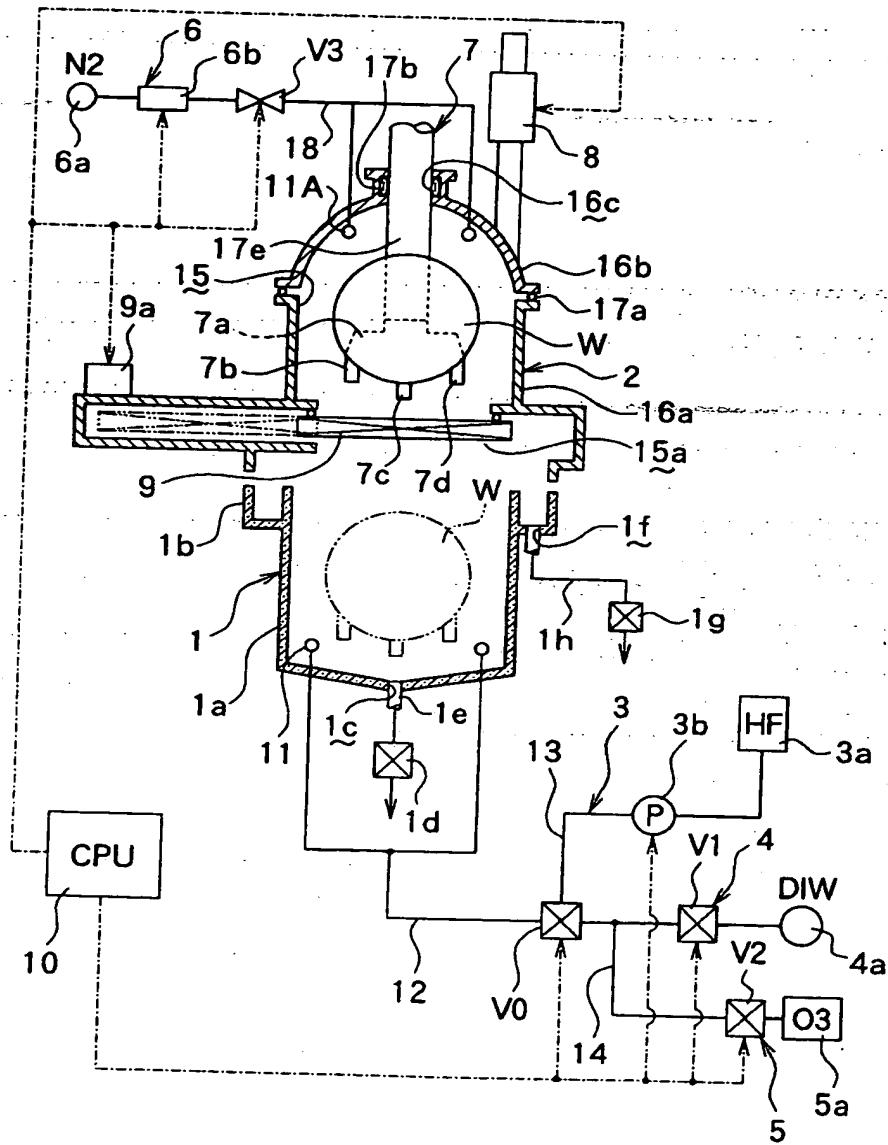


**Title: Method and Apparatus of Processing Surface of Substrate**  
**Inventor(s): TOSHIMA**  
**Application No.: 10/036,787**  
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# FIG. I

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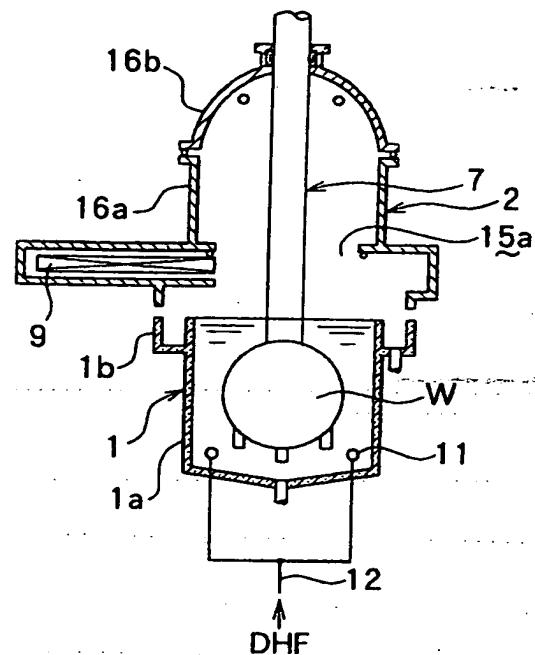


FIG. 2

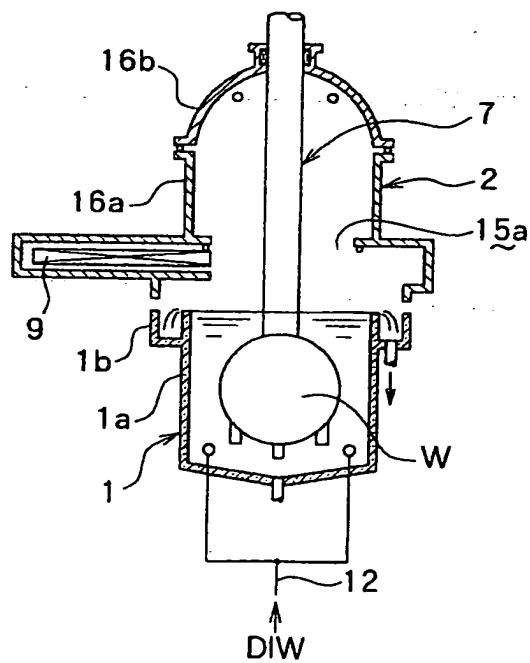


FIG. 3

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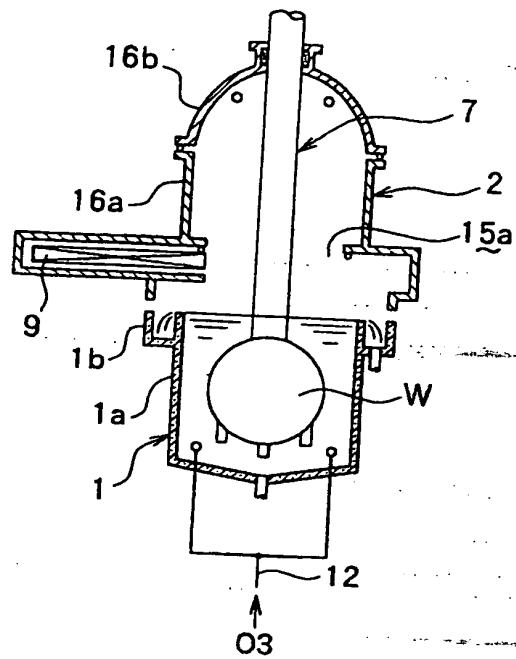


FIG. 4

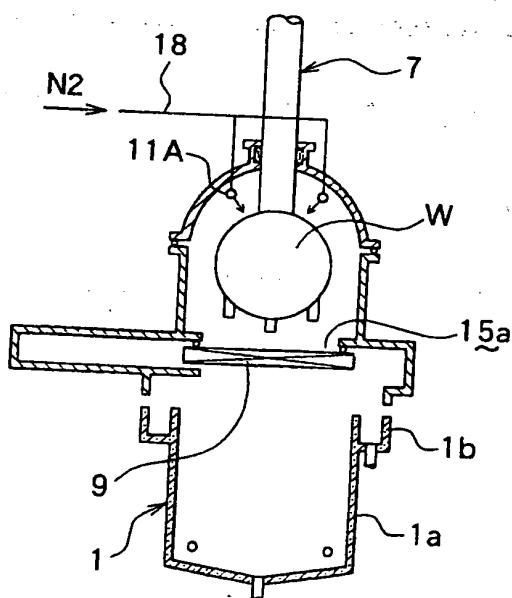


FIG. 5

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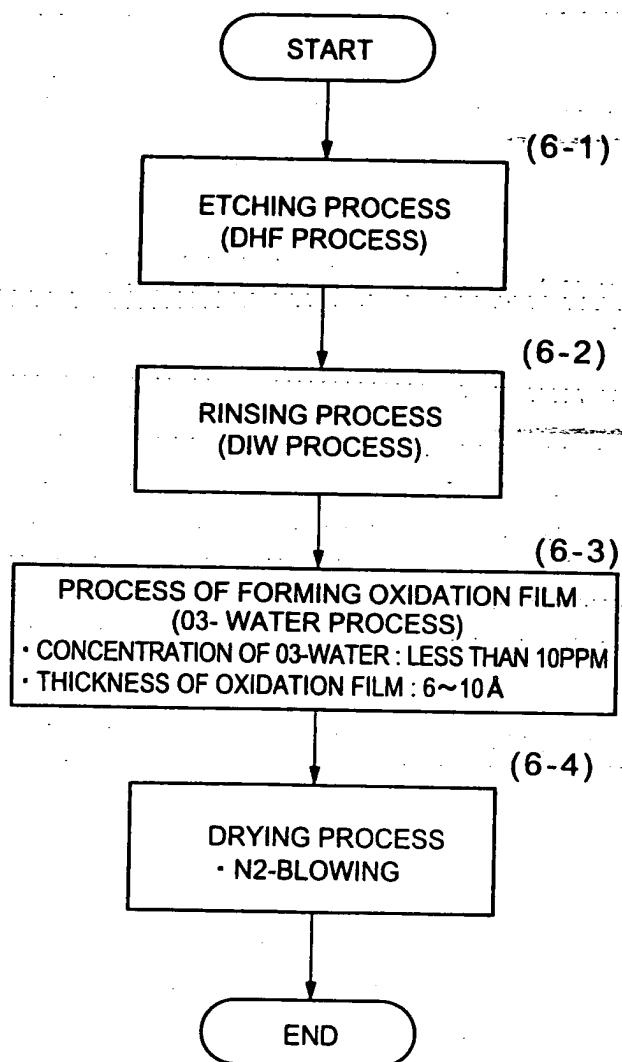


FIG.6

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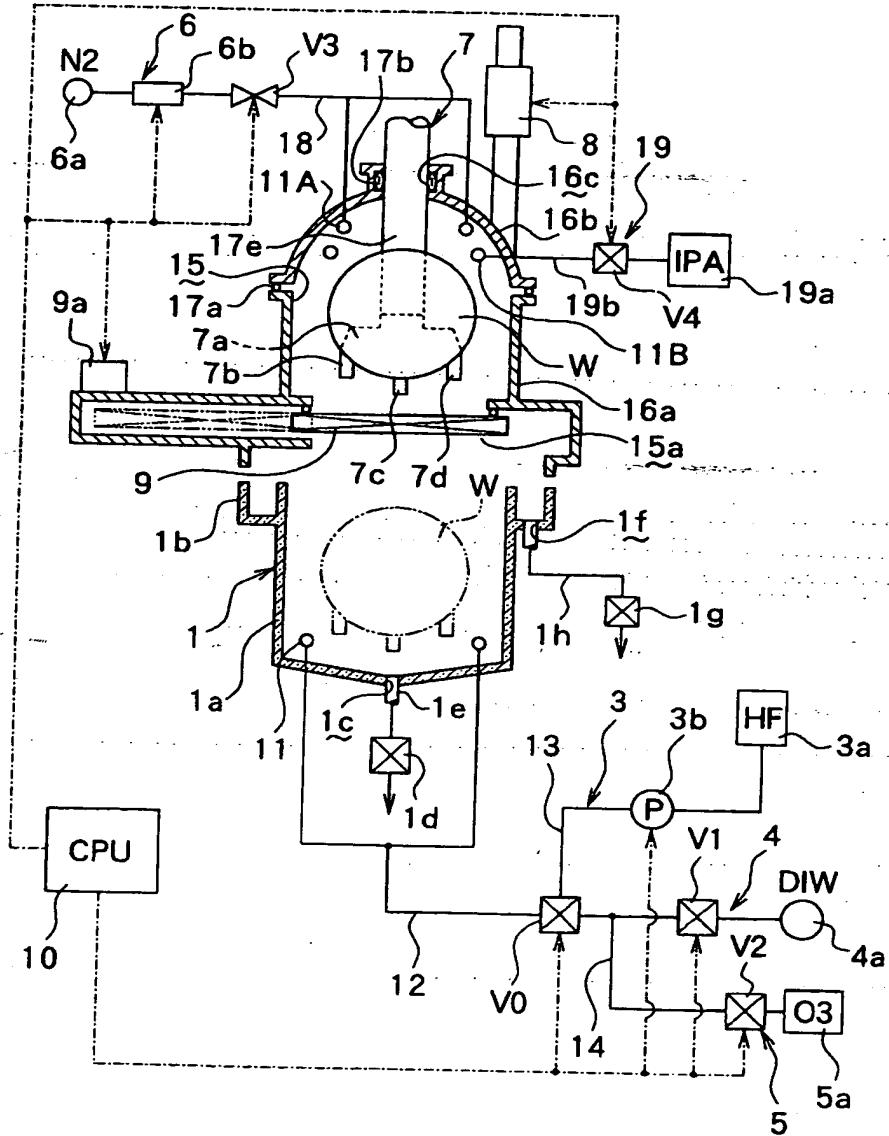


FIG. 7

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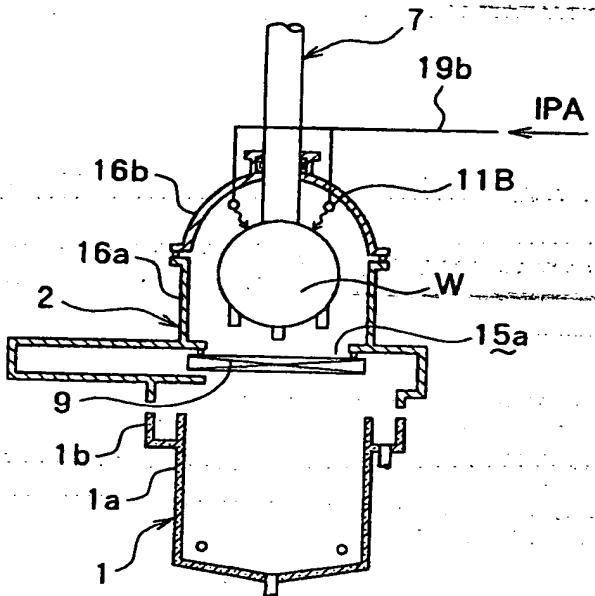


FIG. 8

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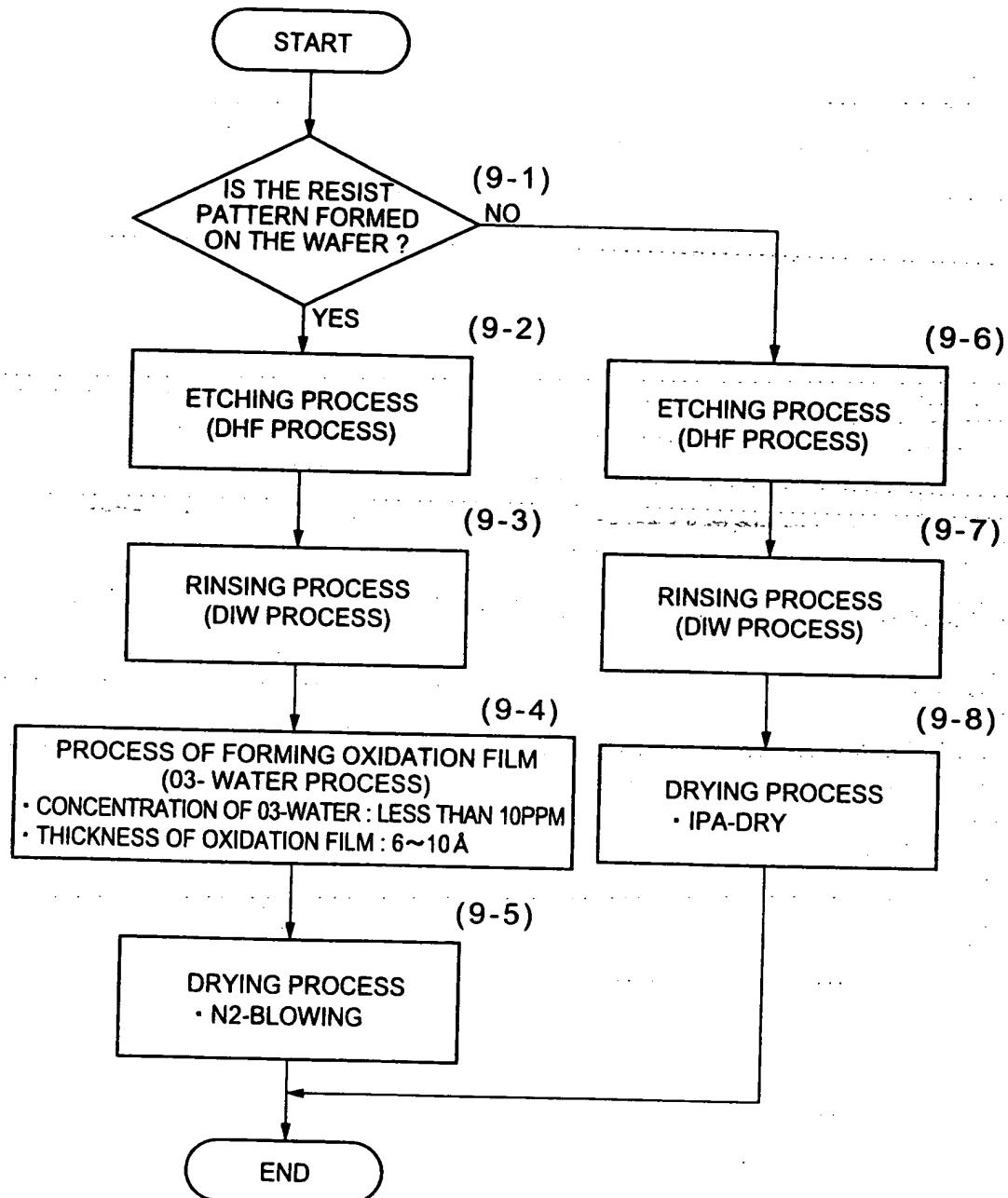
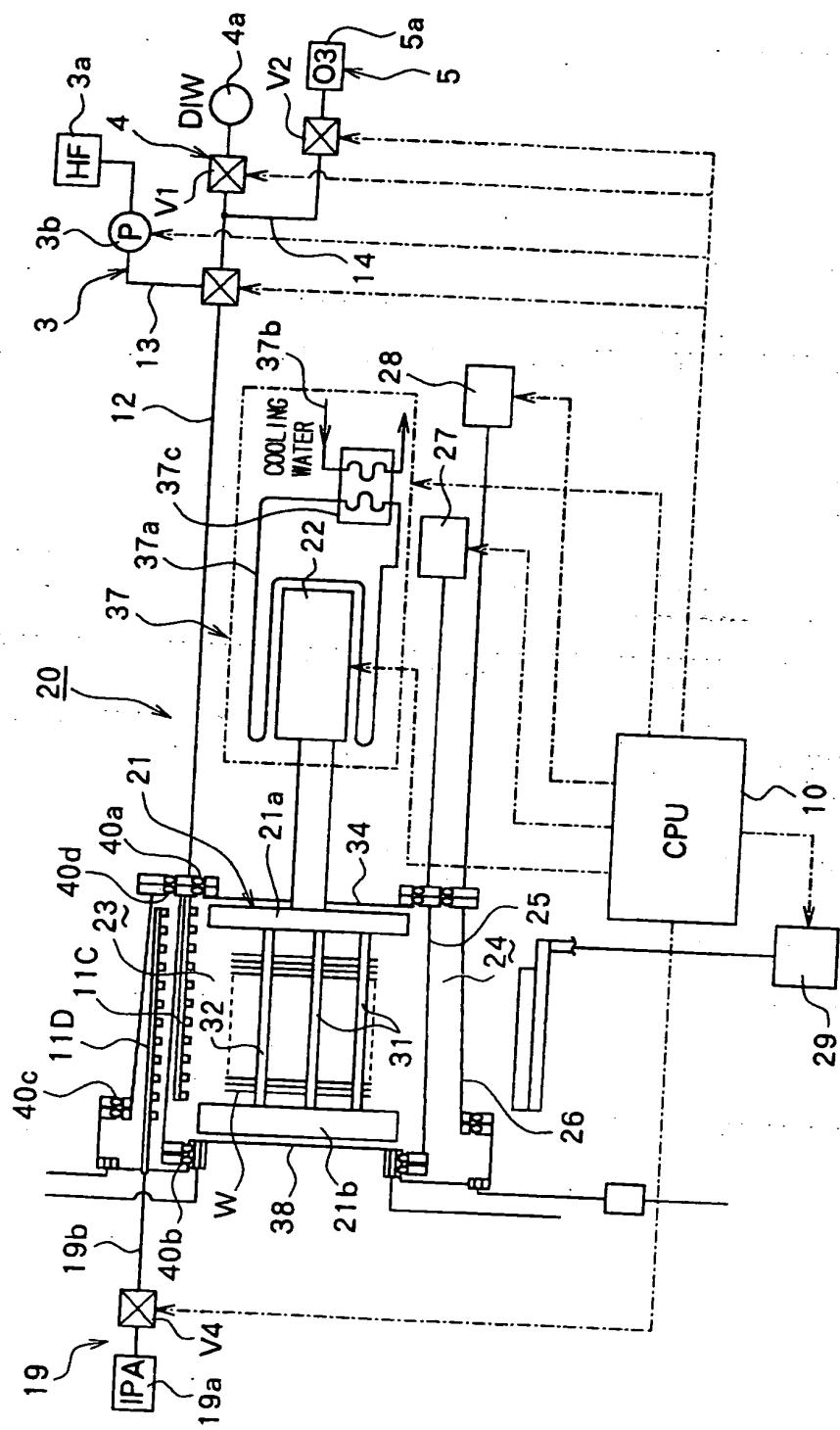


FIG.9

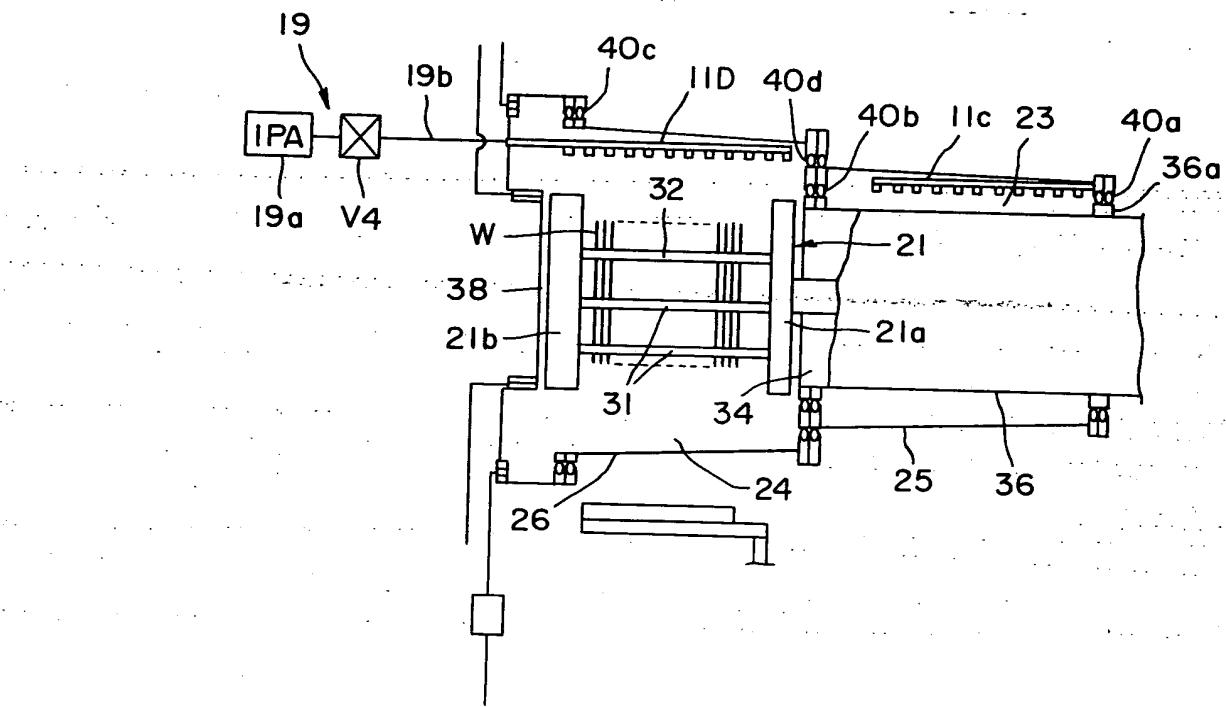
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## FIG. 10A

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## FIG. 10 B

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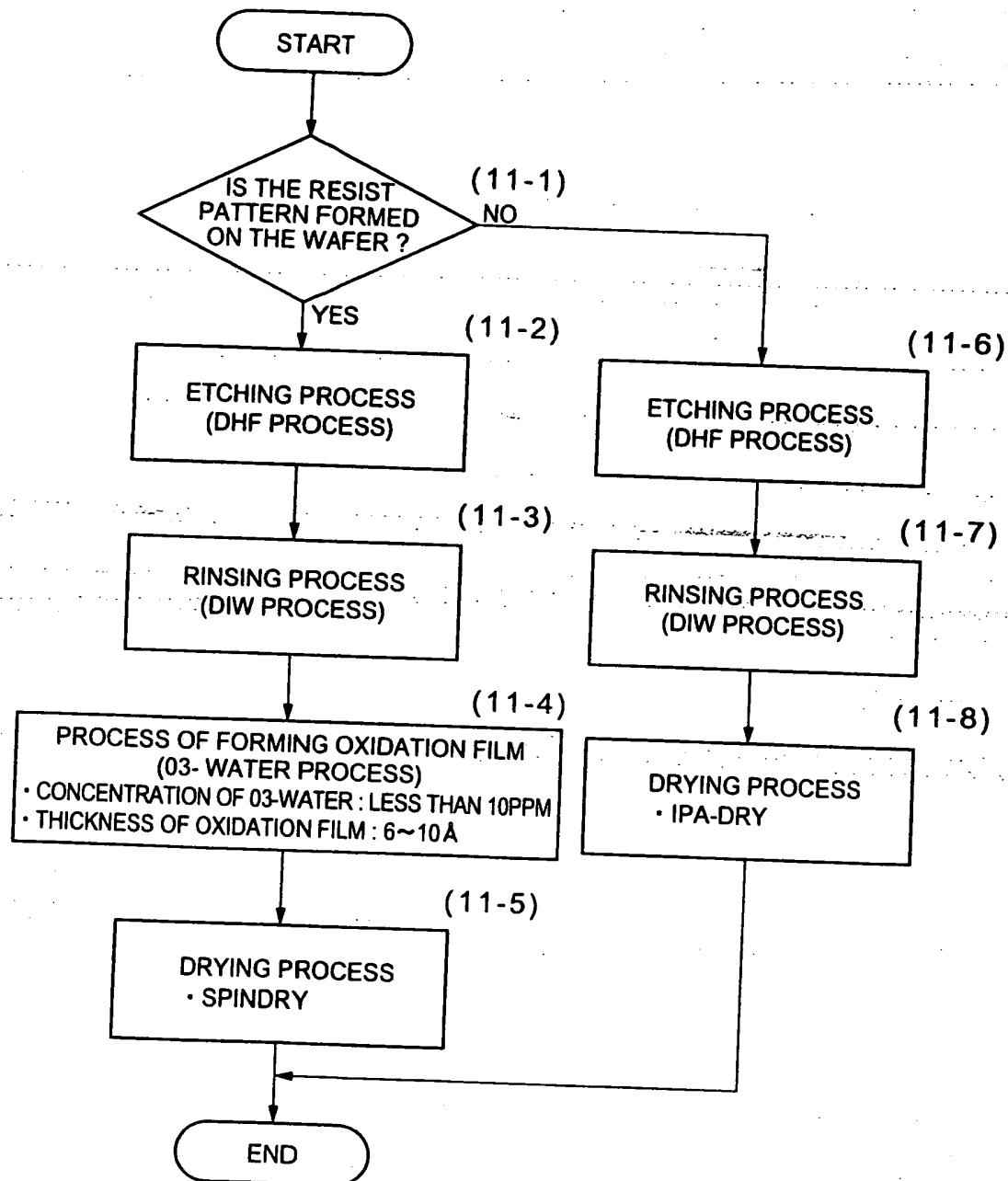


FIG.11

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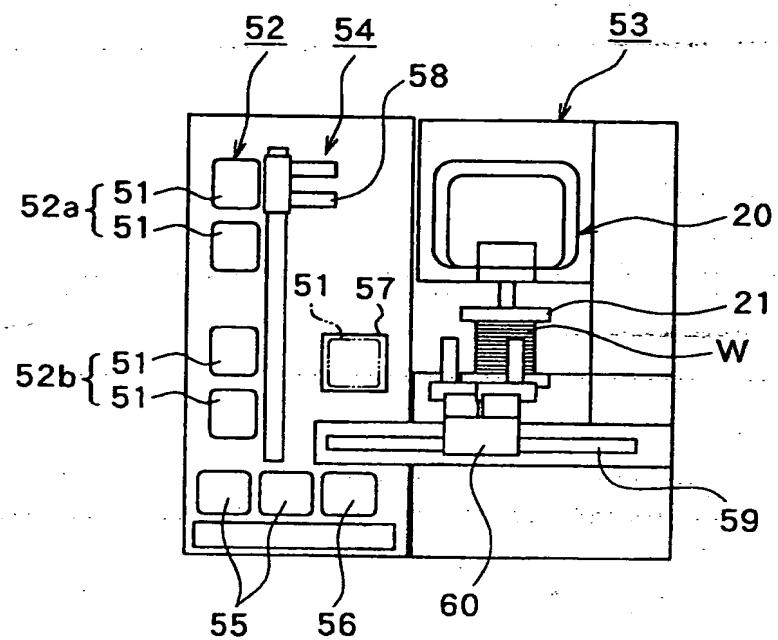


FIG. 12

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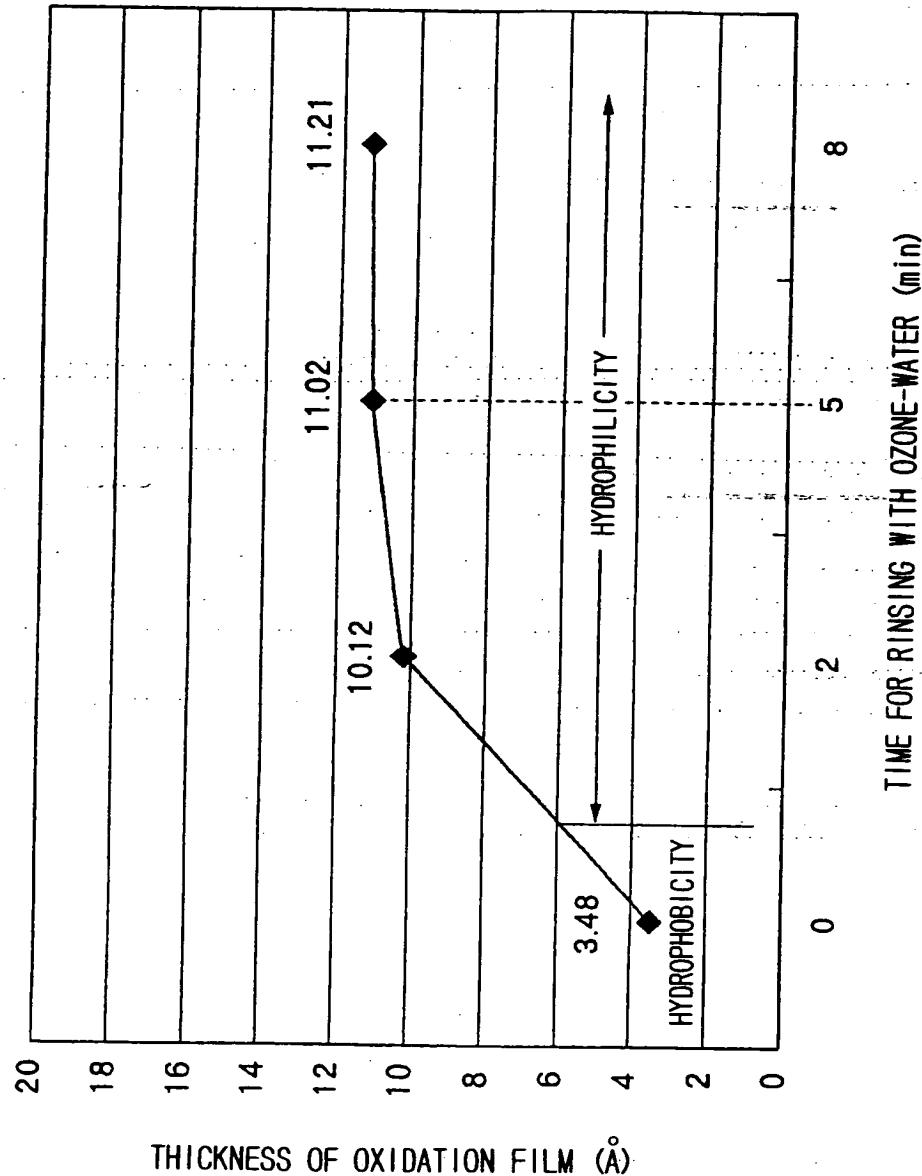


FIG. 13

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Inventor(s): TOSHIMA  
Application No.: 10/036,787  
Docket No.: 199372003600

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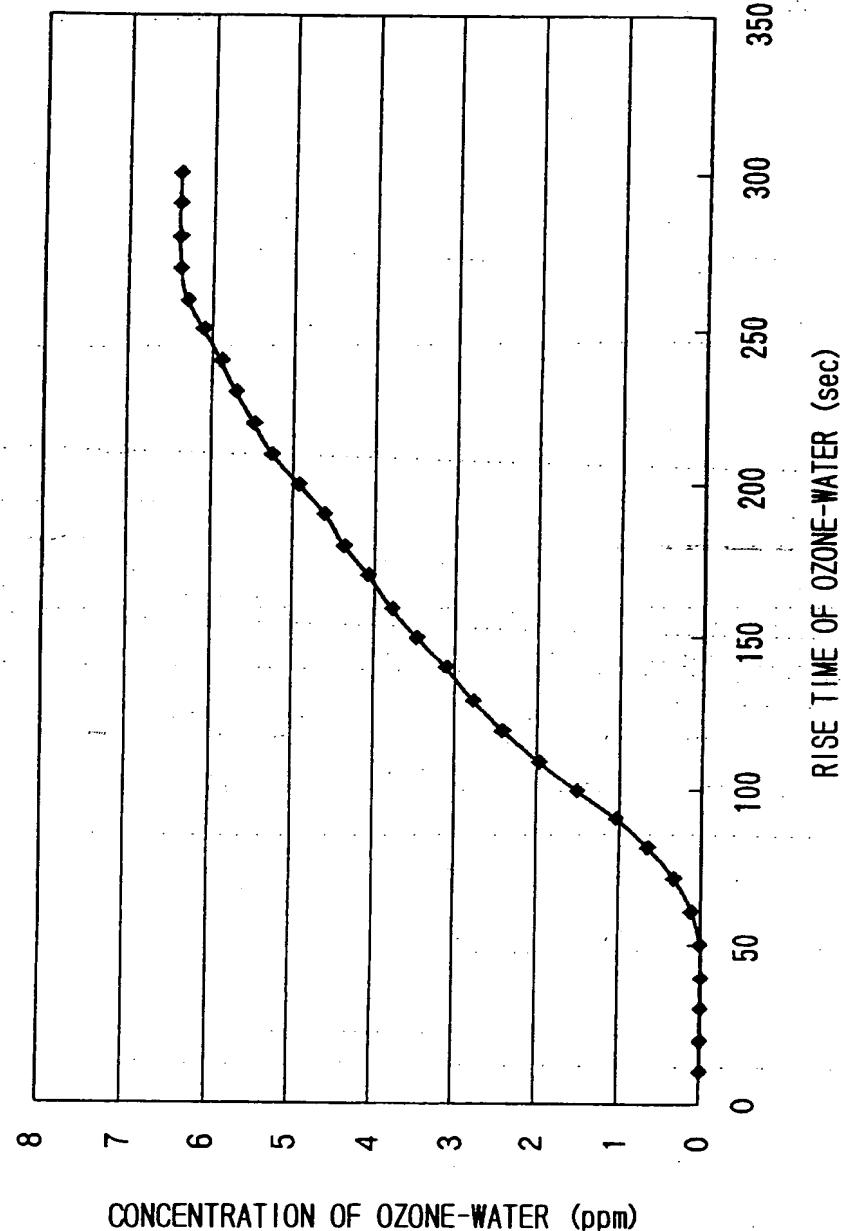


Fig. 14